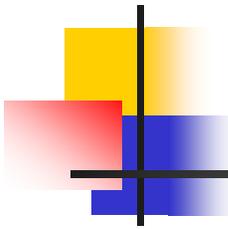


Characterization of AlGaAs/GaAs based QWIPs

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Outline

- **Short introduction**
- **Our activity**
- **Characterization**

Our Activity

Stages of QWIP development

Design and Simulation

Growth
(MOCVD / MBE)

Growth Related
Characterization

Device Processing

Lithography

Metalization

Dielectric
Deposition

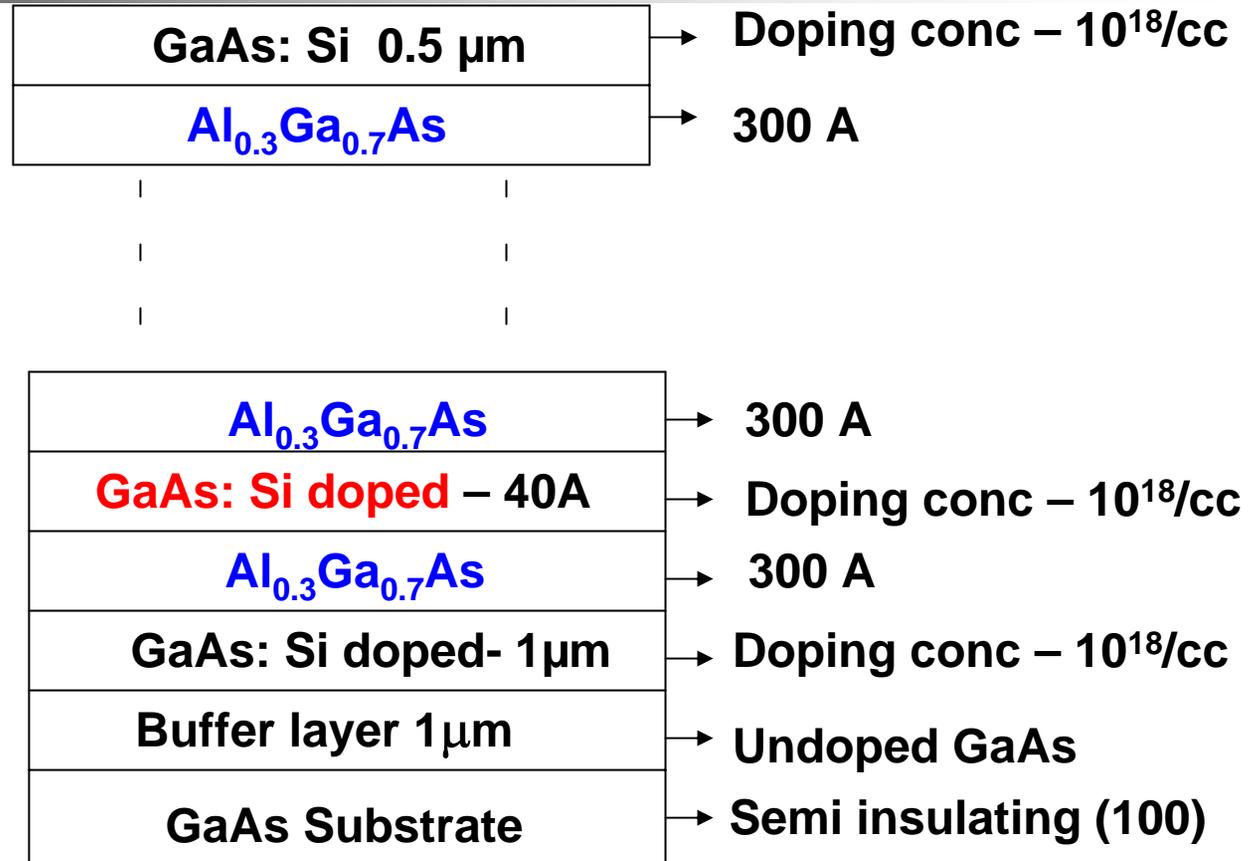
Device
Characterization

Dark Current

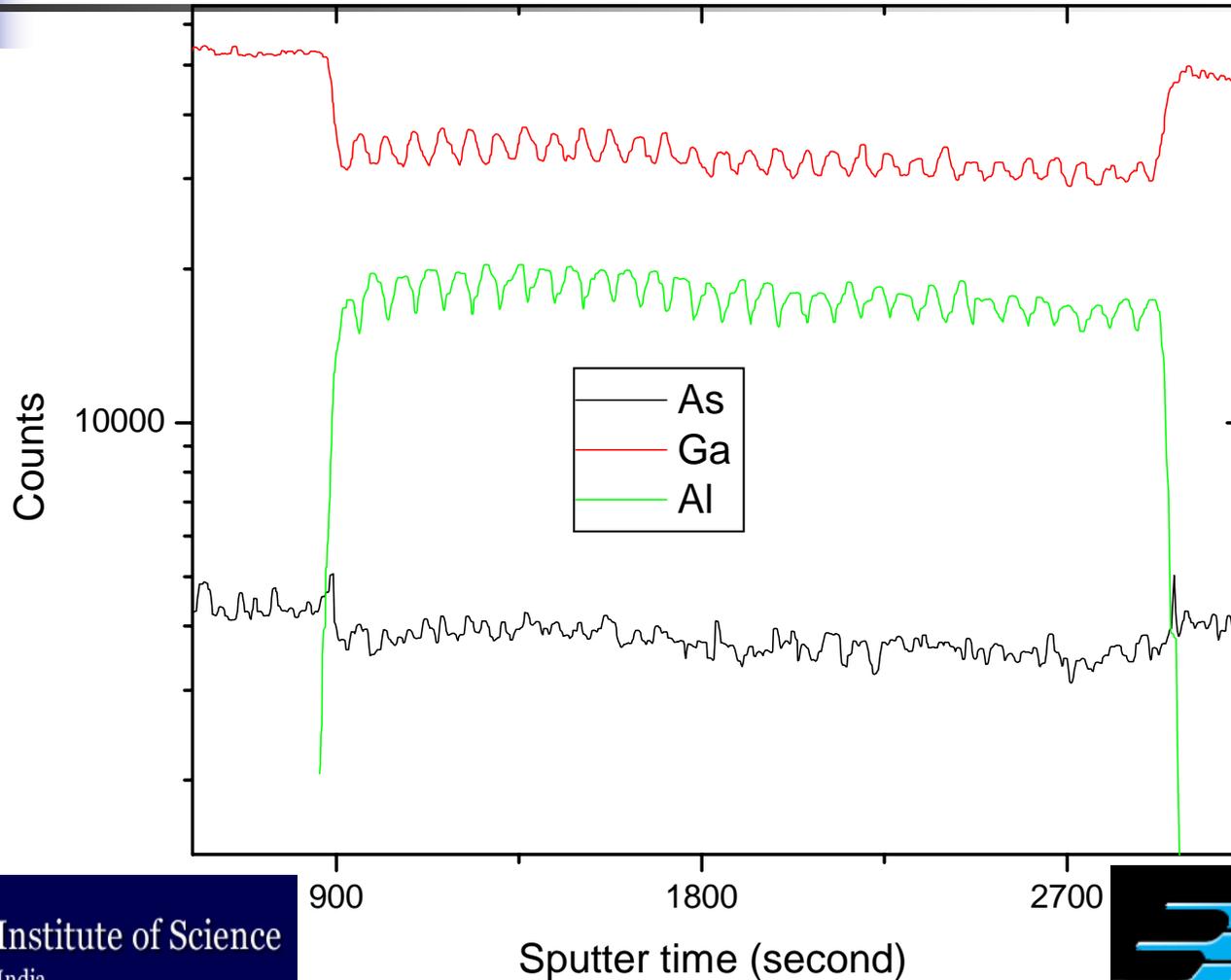
Responsivity



Structure of the MQW (28 - wells)



SIMS Profile of GaAs/AlGaAs QWIP Structure (28 Periods)

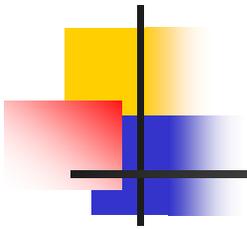




Device processing and Characterization:

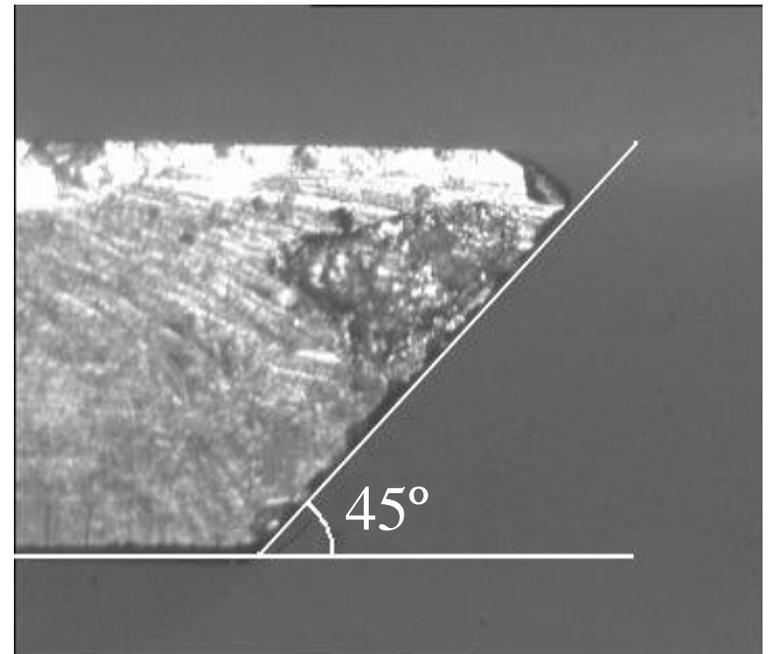
- OPTICAL MICROSCOPE
- SEM
- AFM & DEKTAK

45° EDGE FACET
NORMAL INCIDENCE GRATINGS
C-QWIP

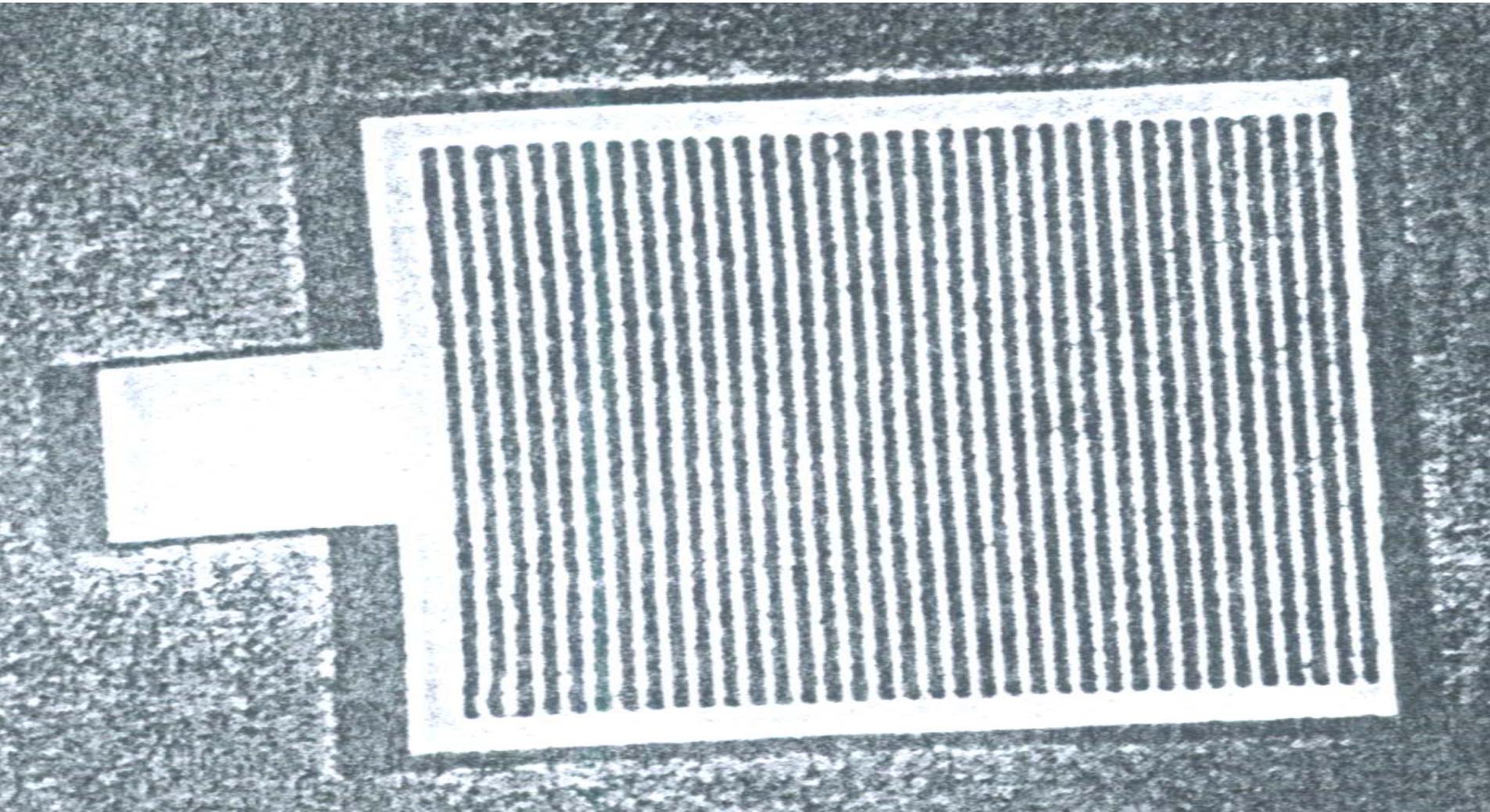


45° Edge Polishing

Al_2O_3 powder ~ 5 - 0.3 μm



METAL GRATING COUPLER



Indian Institute of Science
Bangalore, India

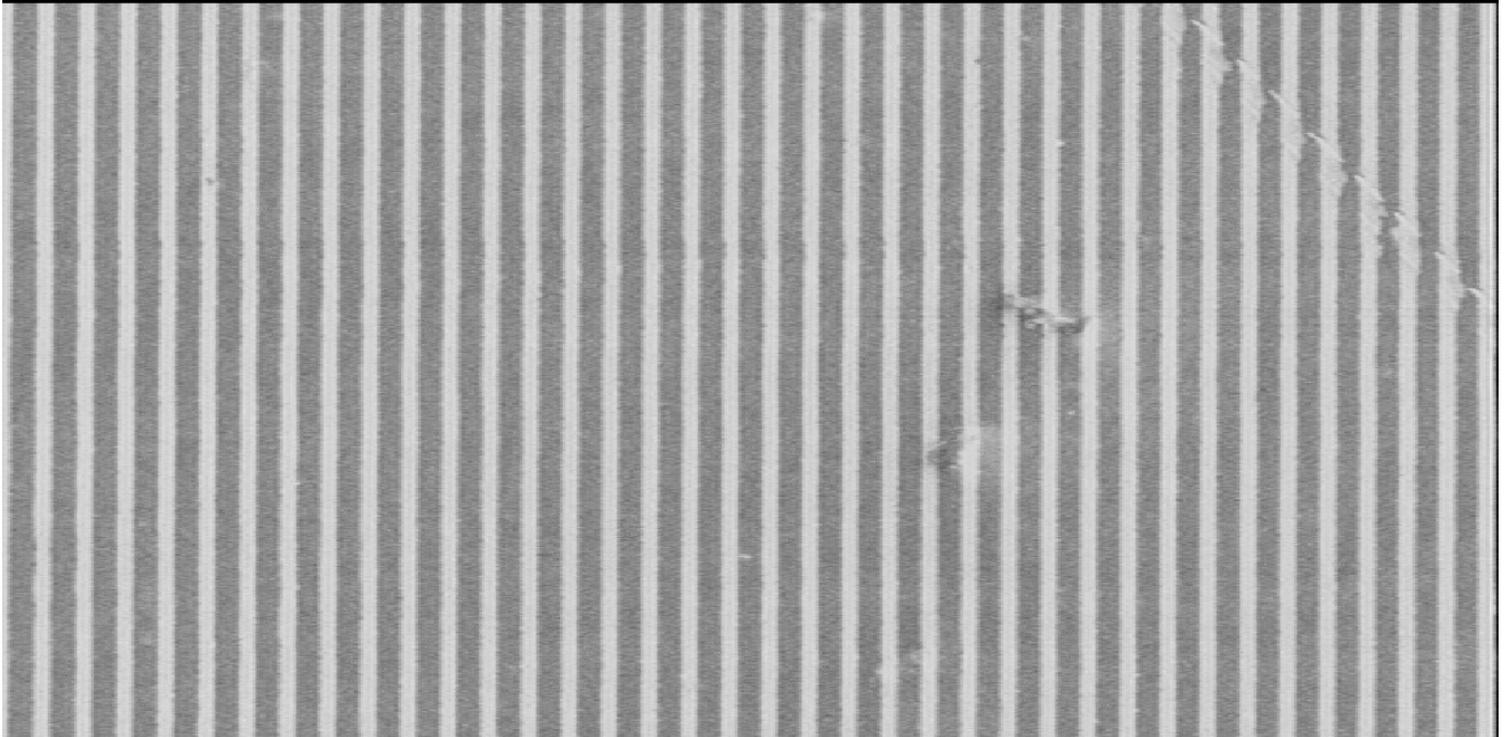
BHARAT ELECTRONICS
QUALITY. TECHNOLOGY. INNOVATION.

Under-cut profile of S1813 photoresist after image reversal used for lift-off

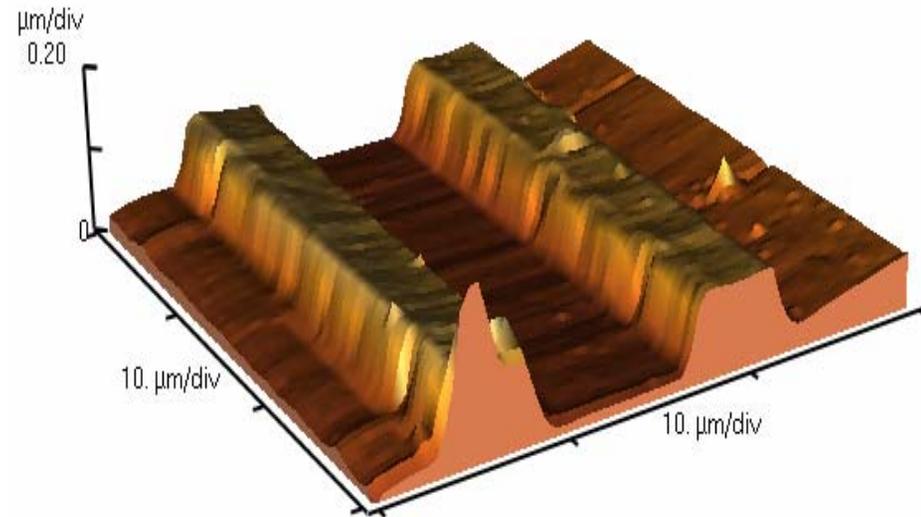
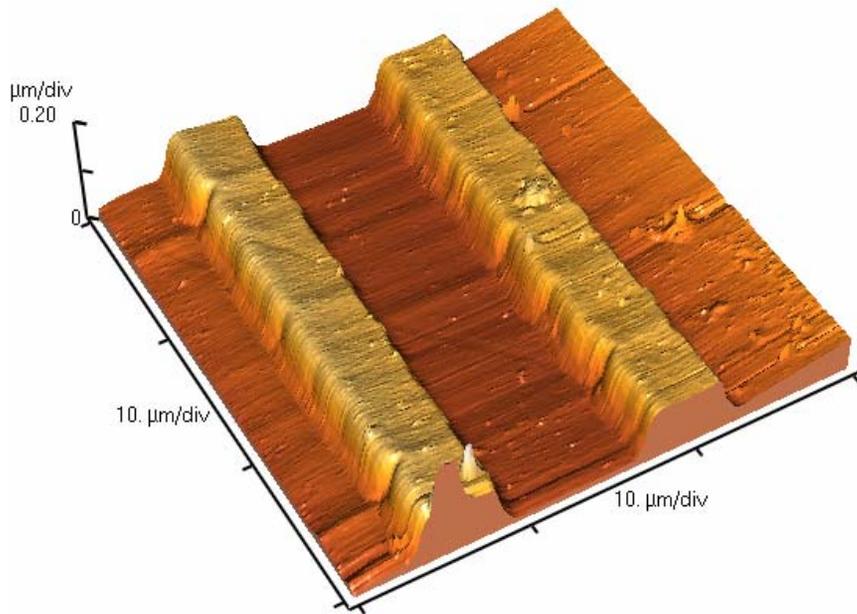


Front grid pattern (*Lift-Off Lithography*)

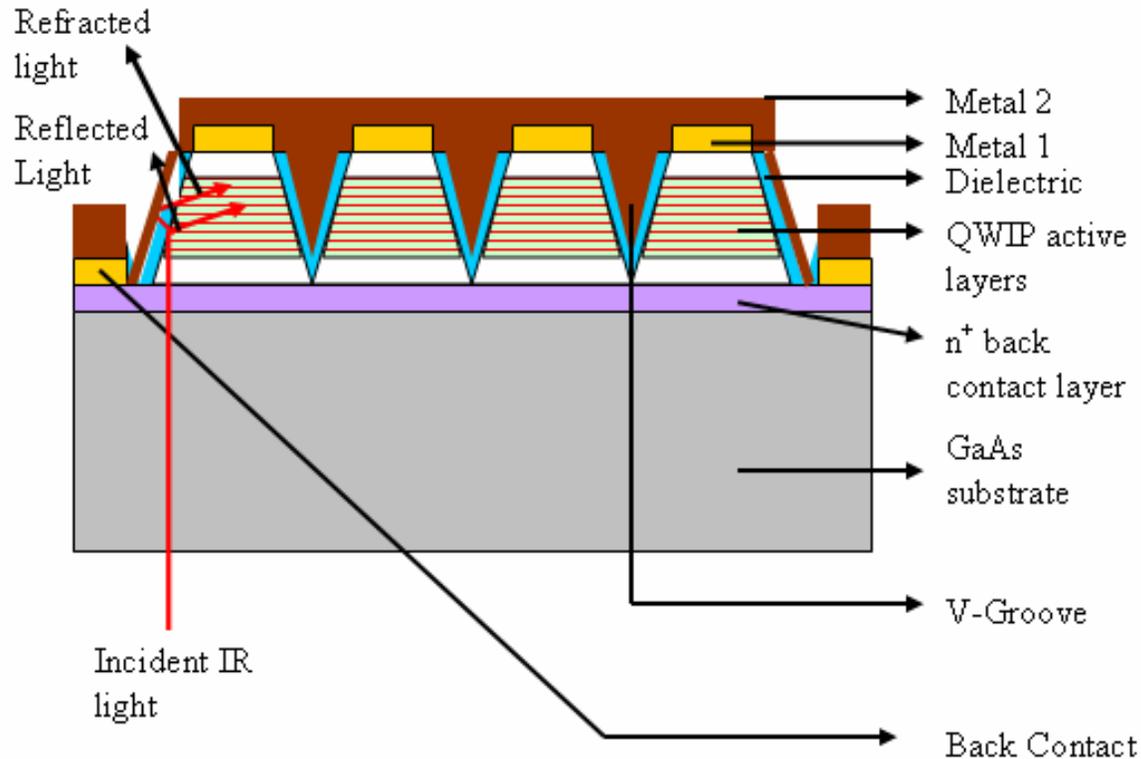
L= SE1 EHT= 20.0 KV WD= 22 mm MAG= X 260. PHOTO= 1
100 µm F

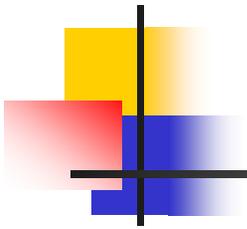


AFM surface topography study: 3D view of two fingers

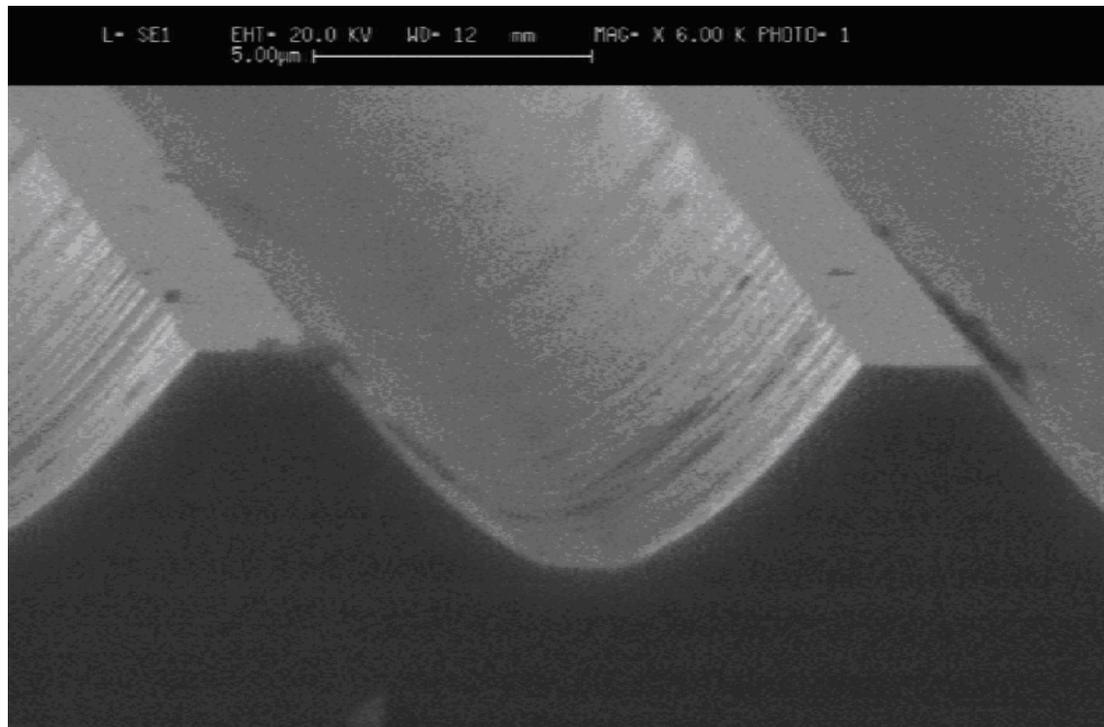


Cross-sectional View of the C-QWIP

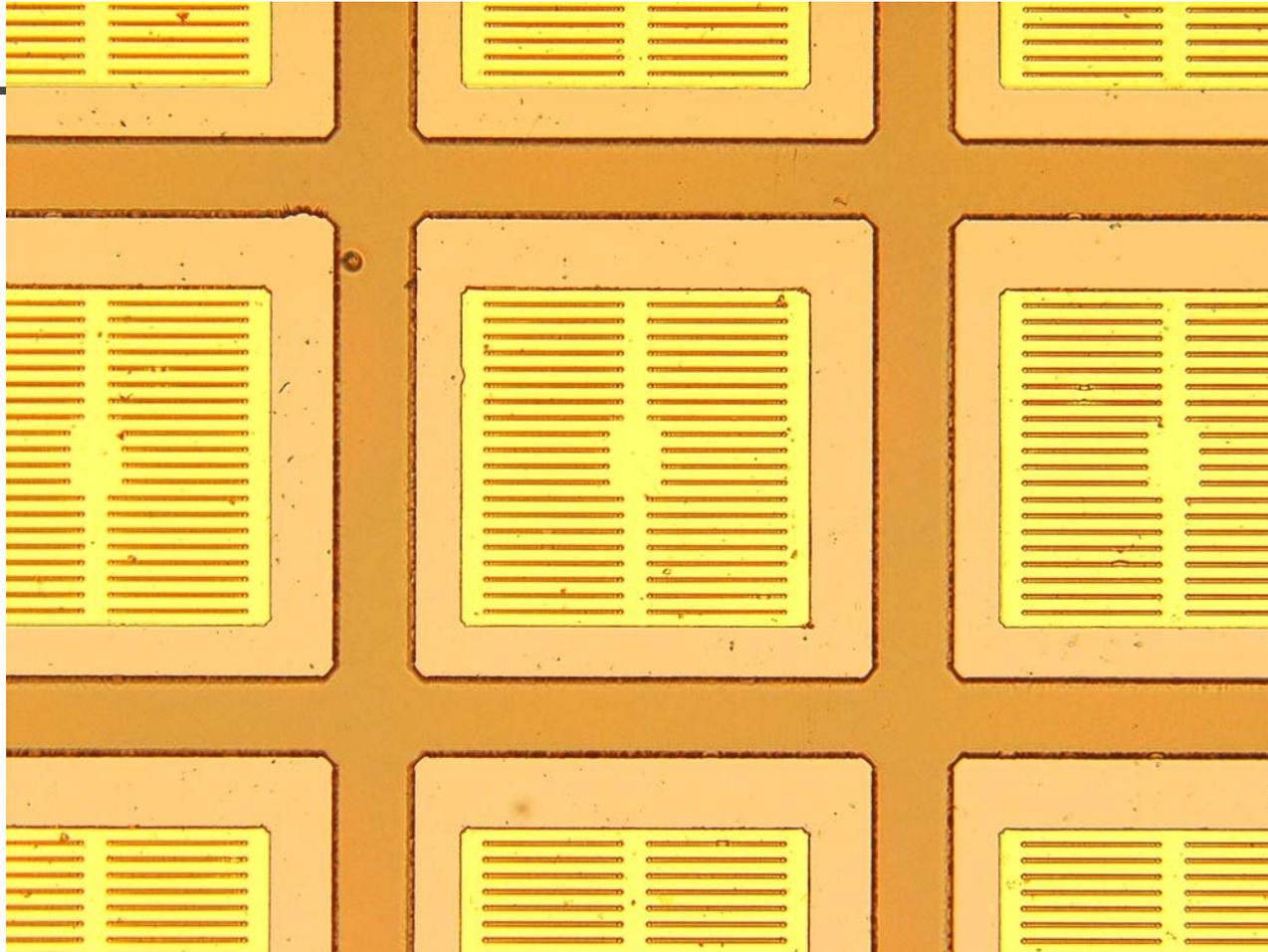




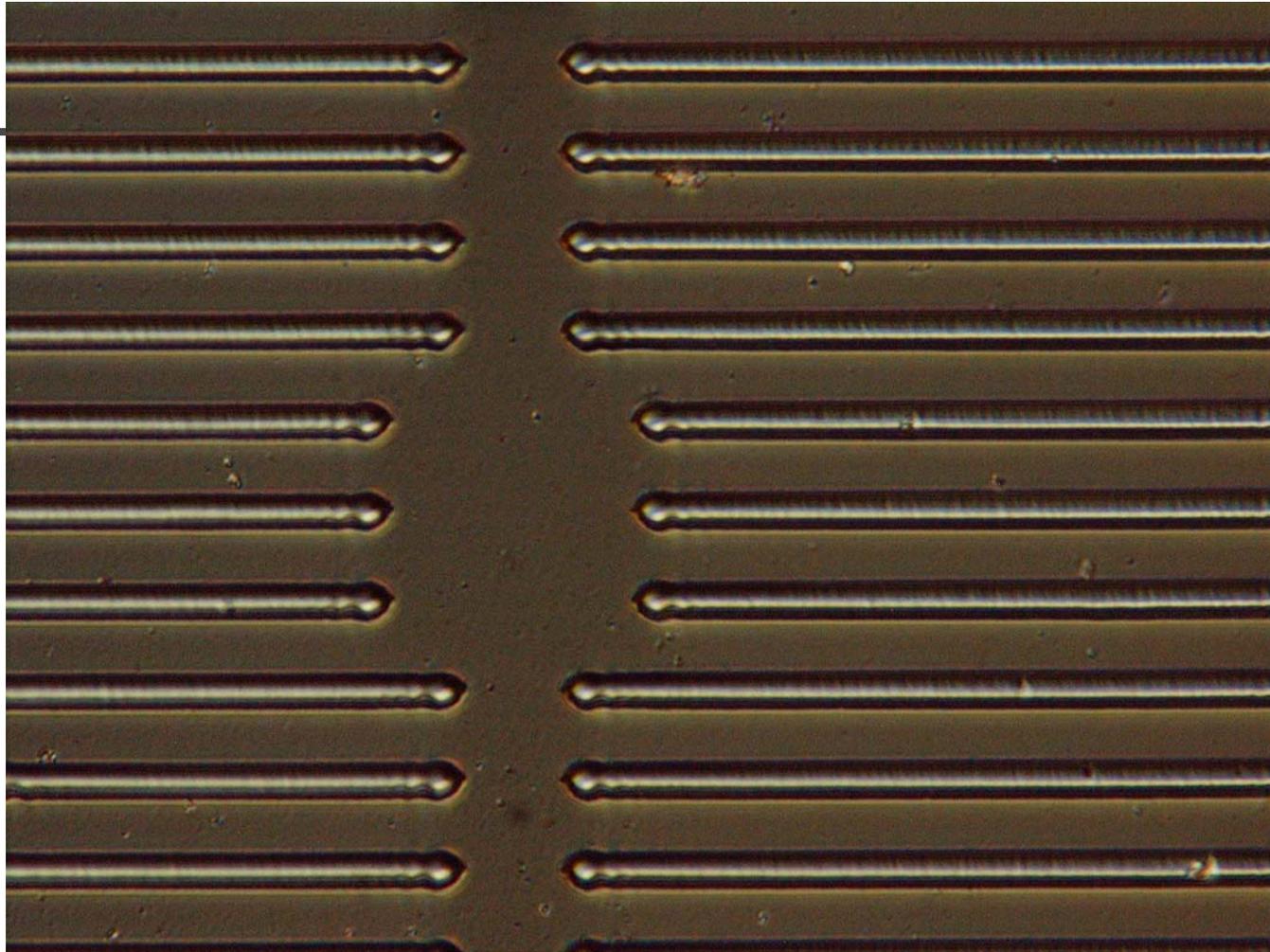
C-QWIP angle determination from SEM



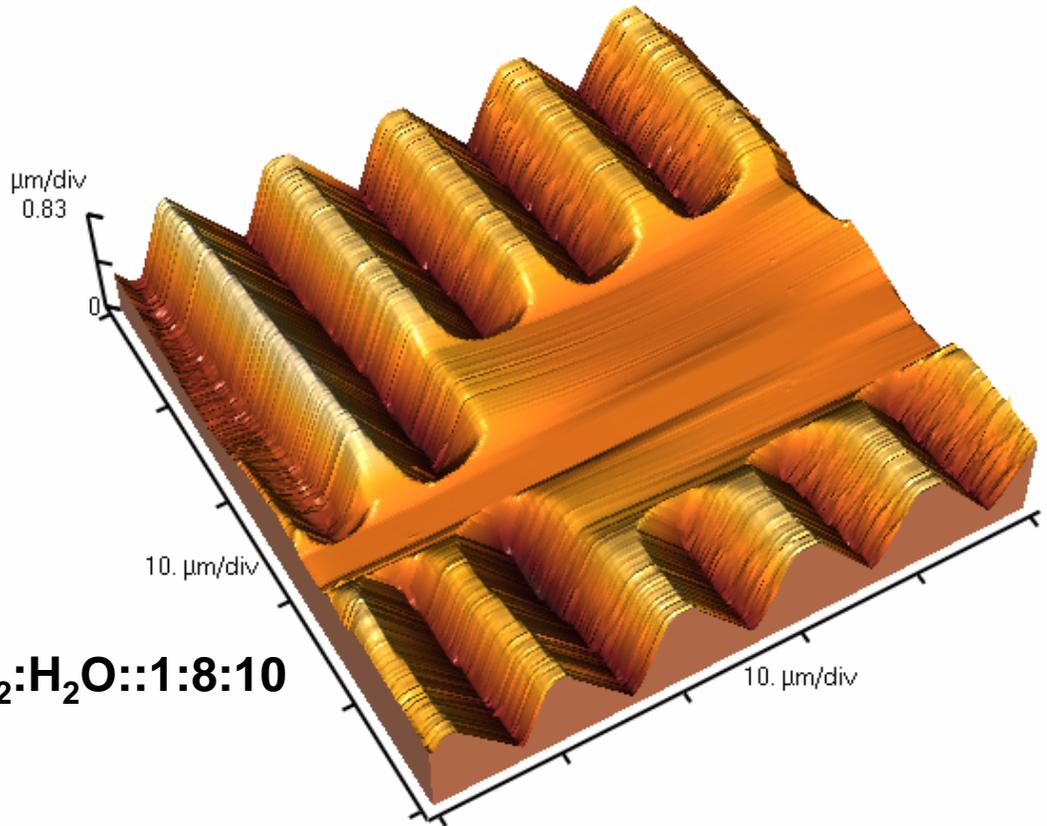
Bright field optical microscope view of the section of the fabricated C-QWIP array (100X)



Dark Field Optical Microscope image of C-QWIP (500X)



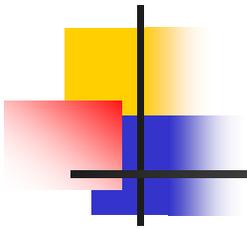
AFM Micrograph of the V-groove structure (C-QWIP)



Periodicity : 10 μm

Etching solution : $\text{H}_2\text{SO}_4:\text{H}_2\text{O}_2:\text{H}_2\text{O}::1:8:10$

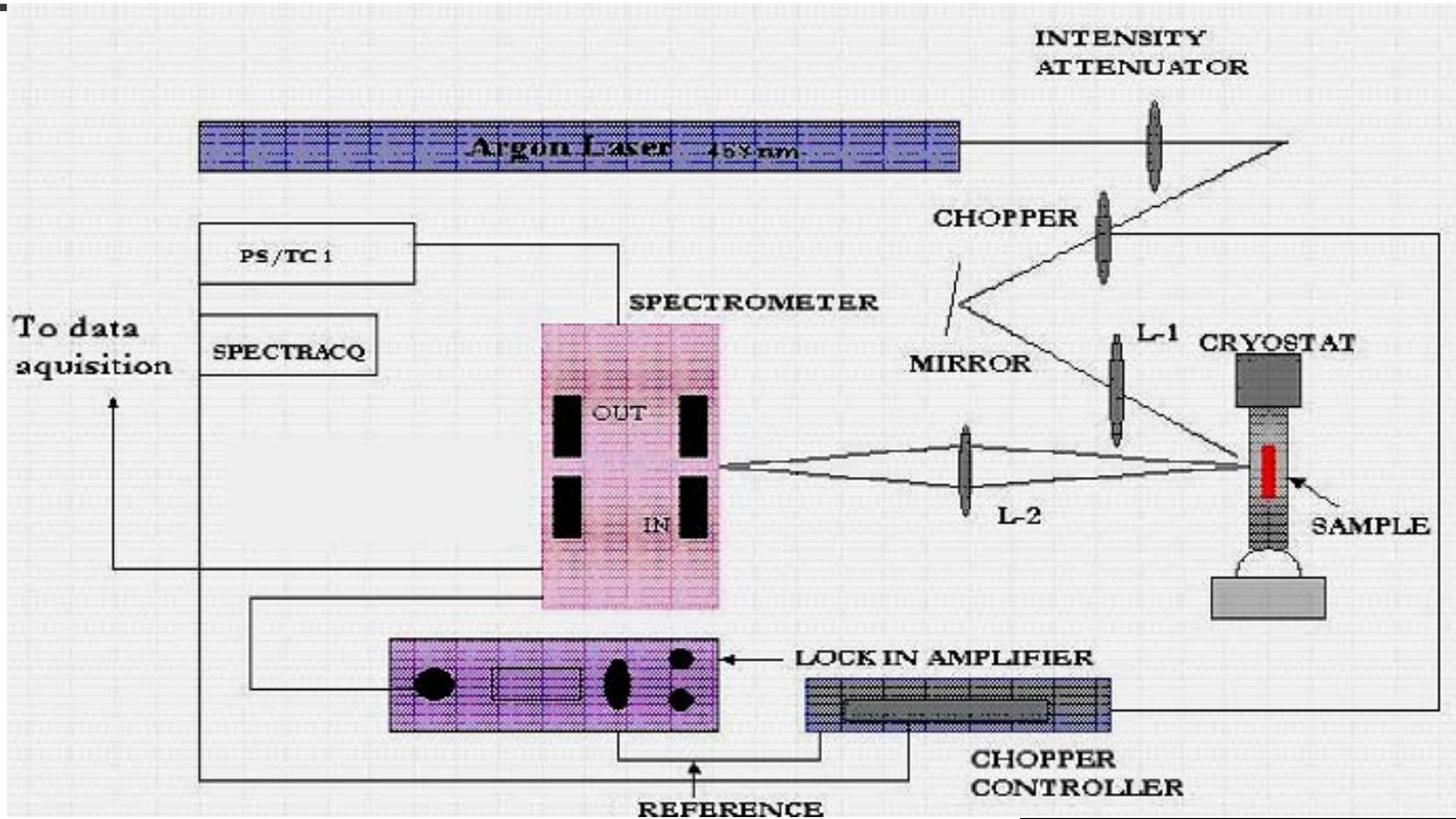
Etching time: 20 sec

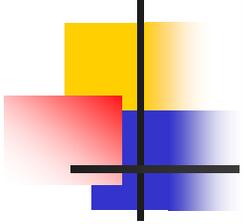
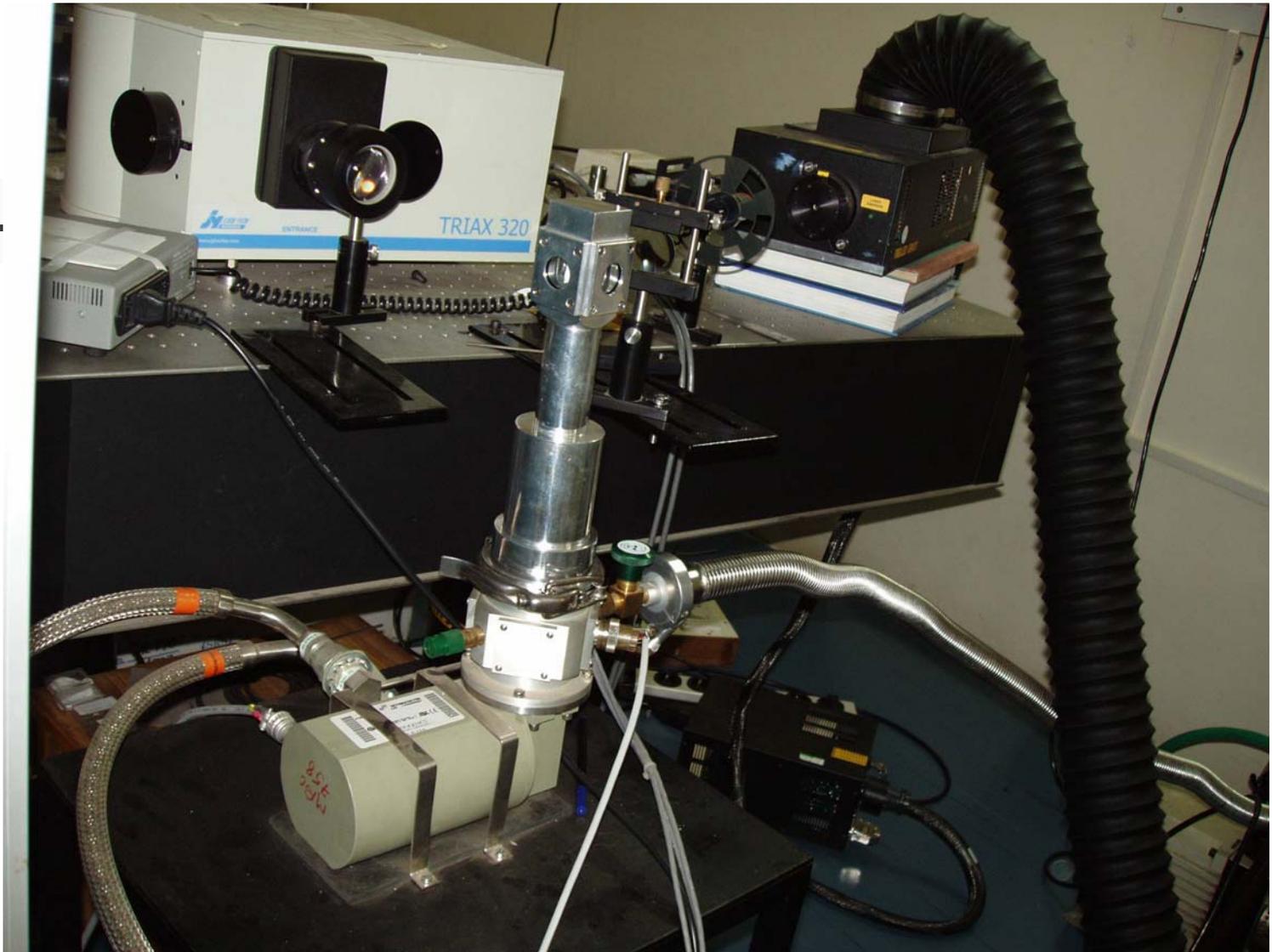


Device characterization

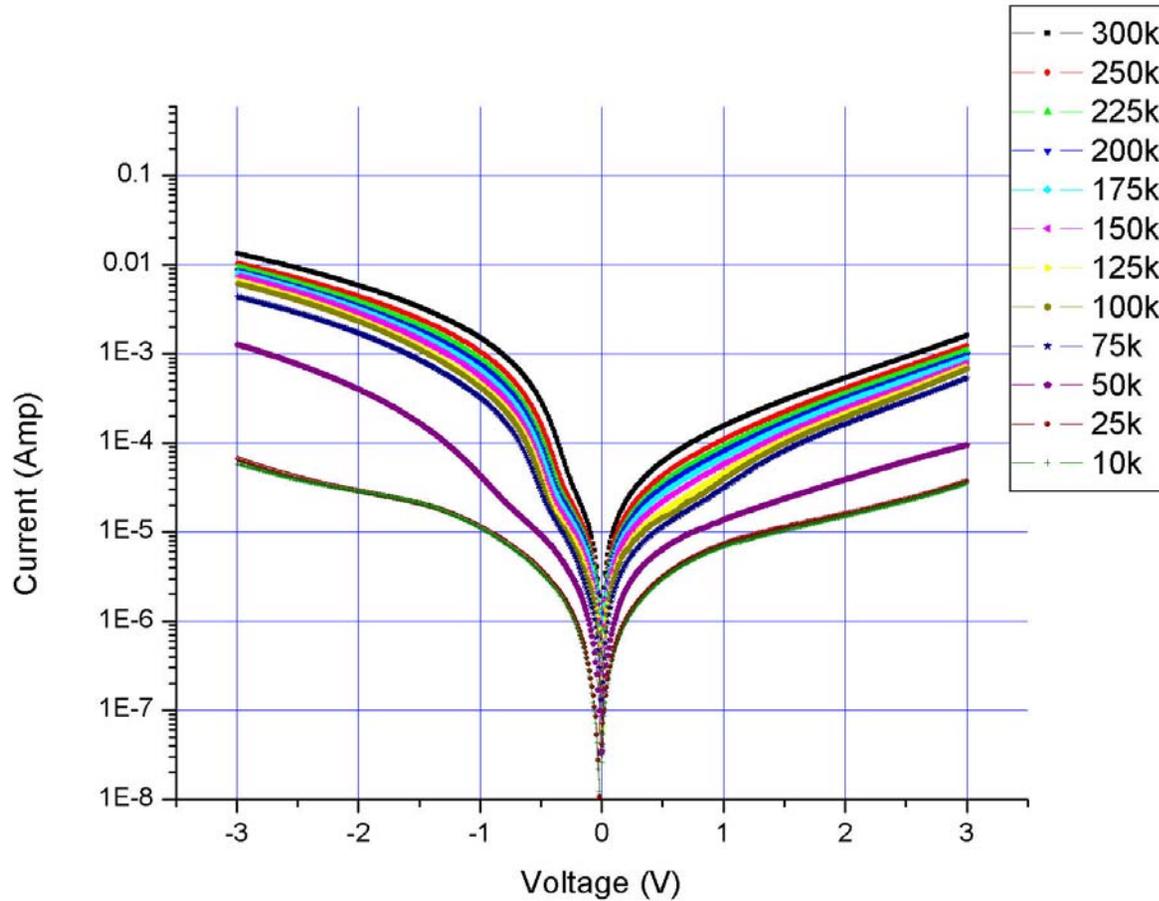
- Dark current measurement
- Illuminated current measurement
- Spectral Response measurement

Optical Characterization Set-Up

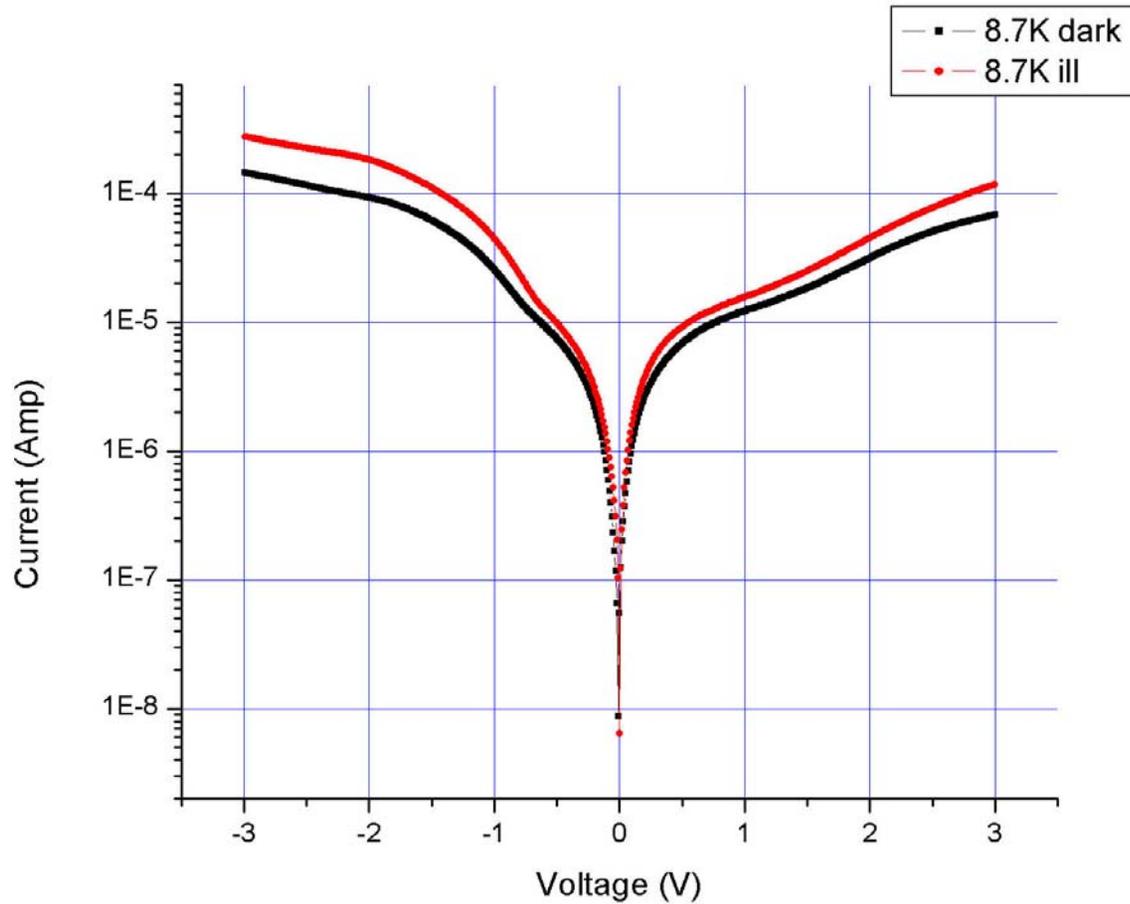




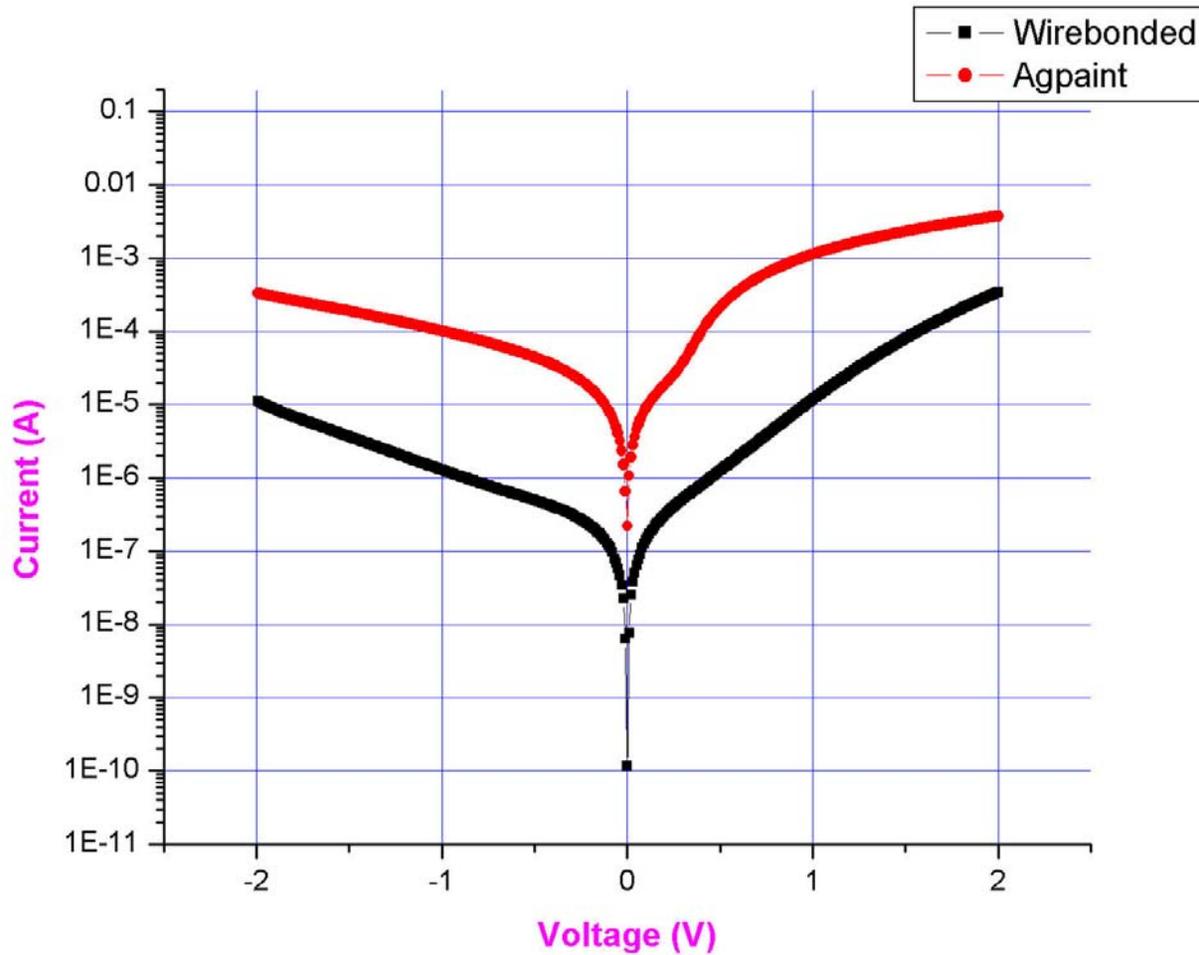
Dark current measurement as a function of temperature



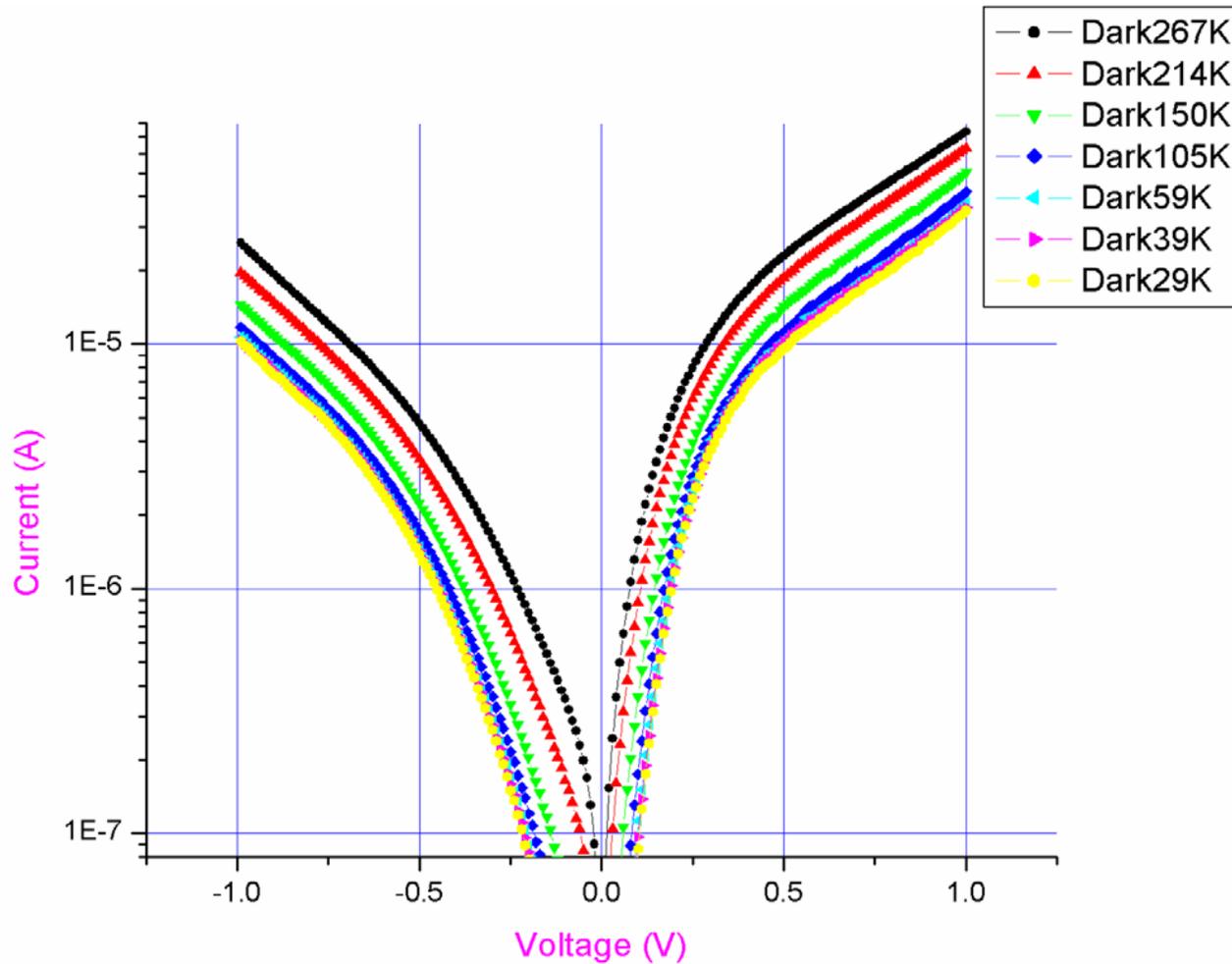
Dark & Illuminated current obtained at 8.7 K



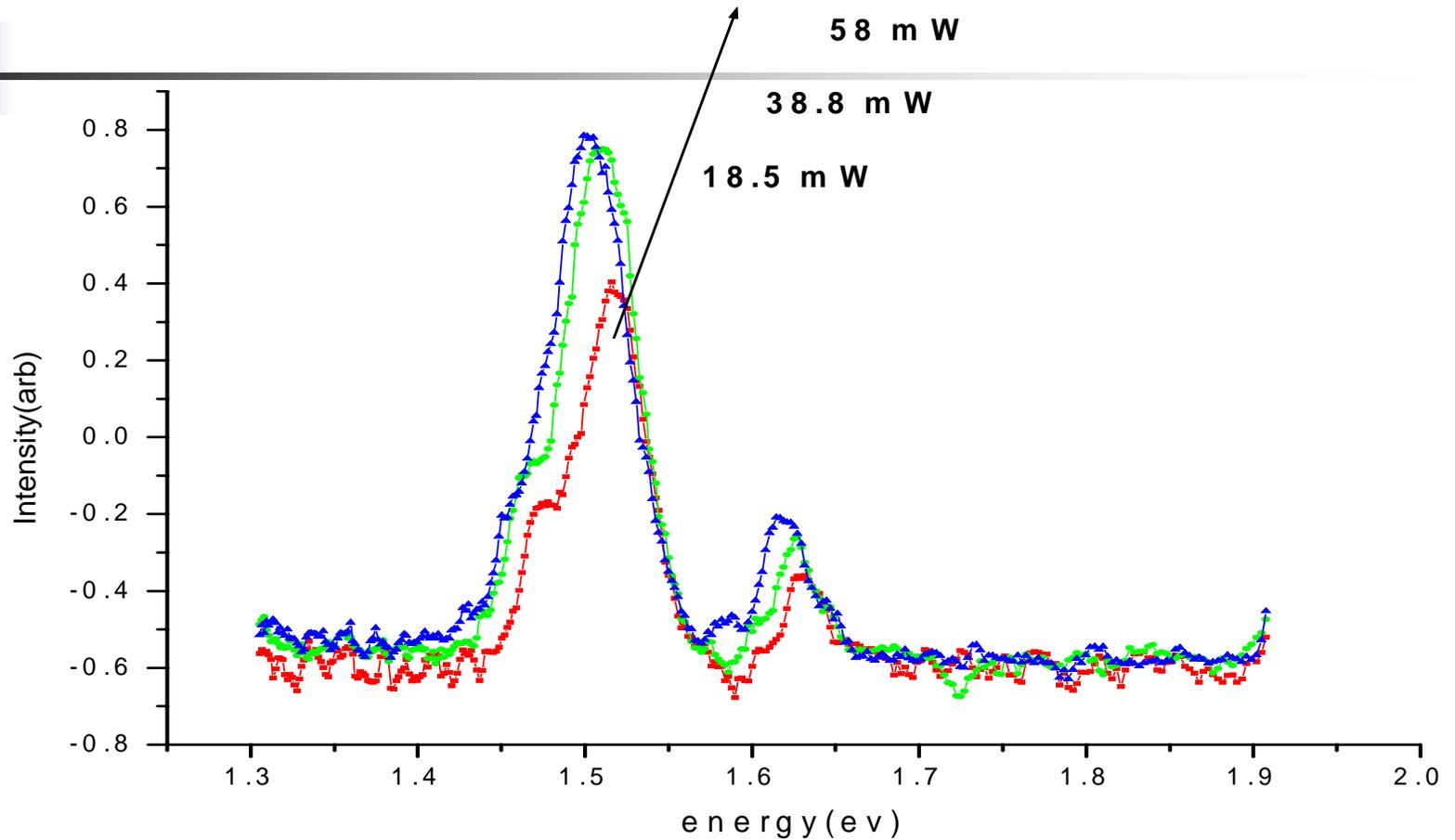
Effect of wire-bonded contact on dark current



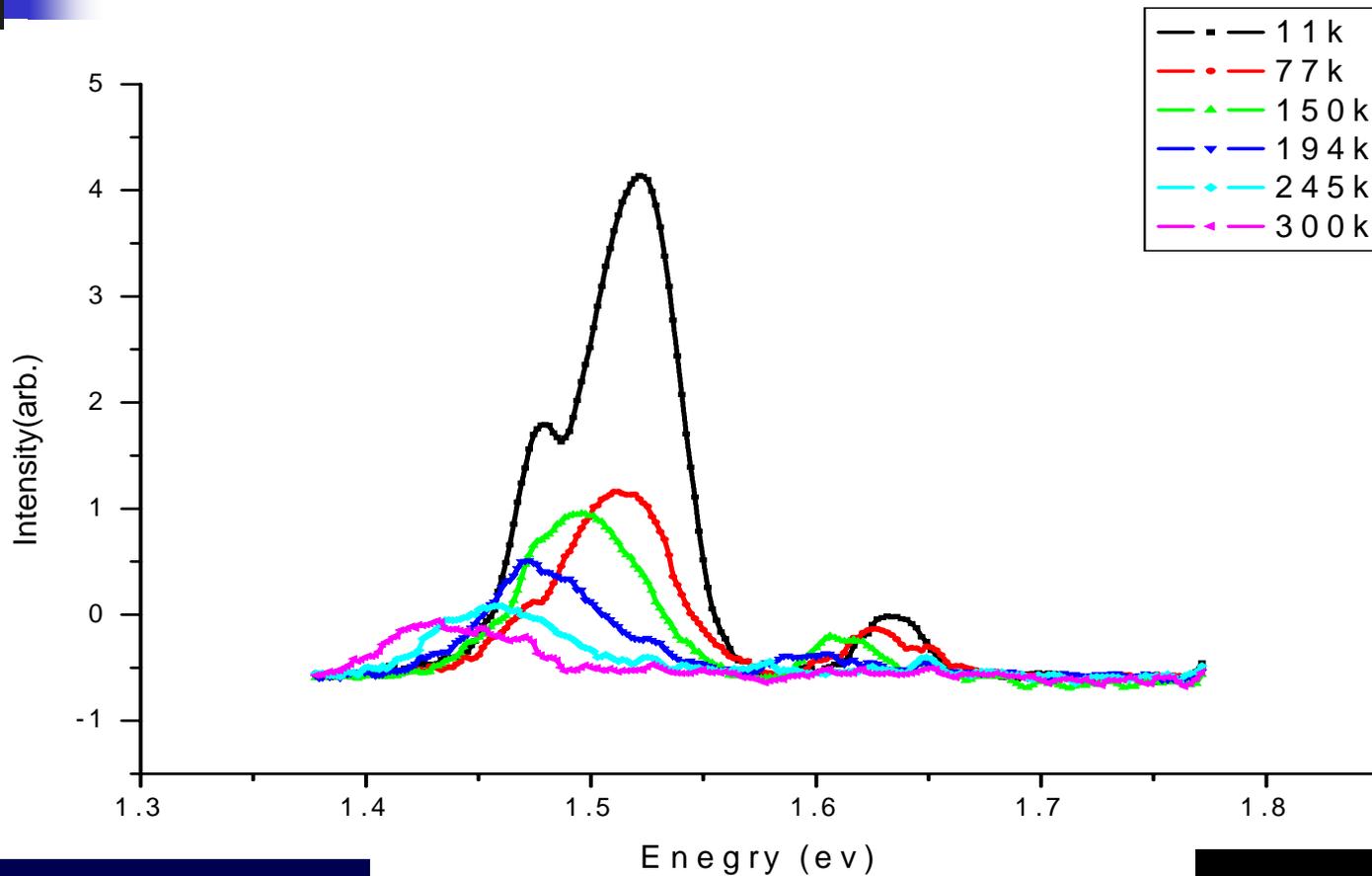
Dark current as a function of temperature (wire-bonded)



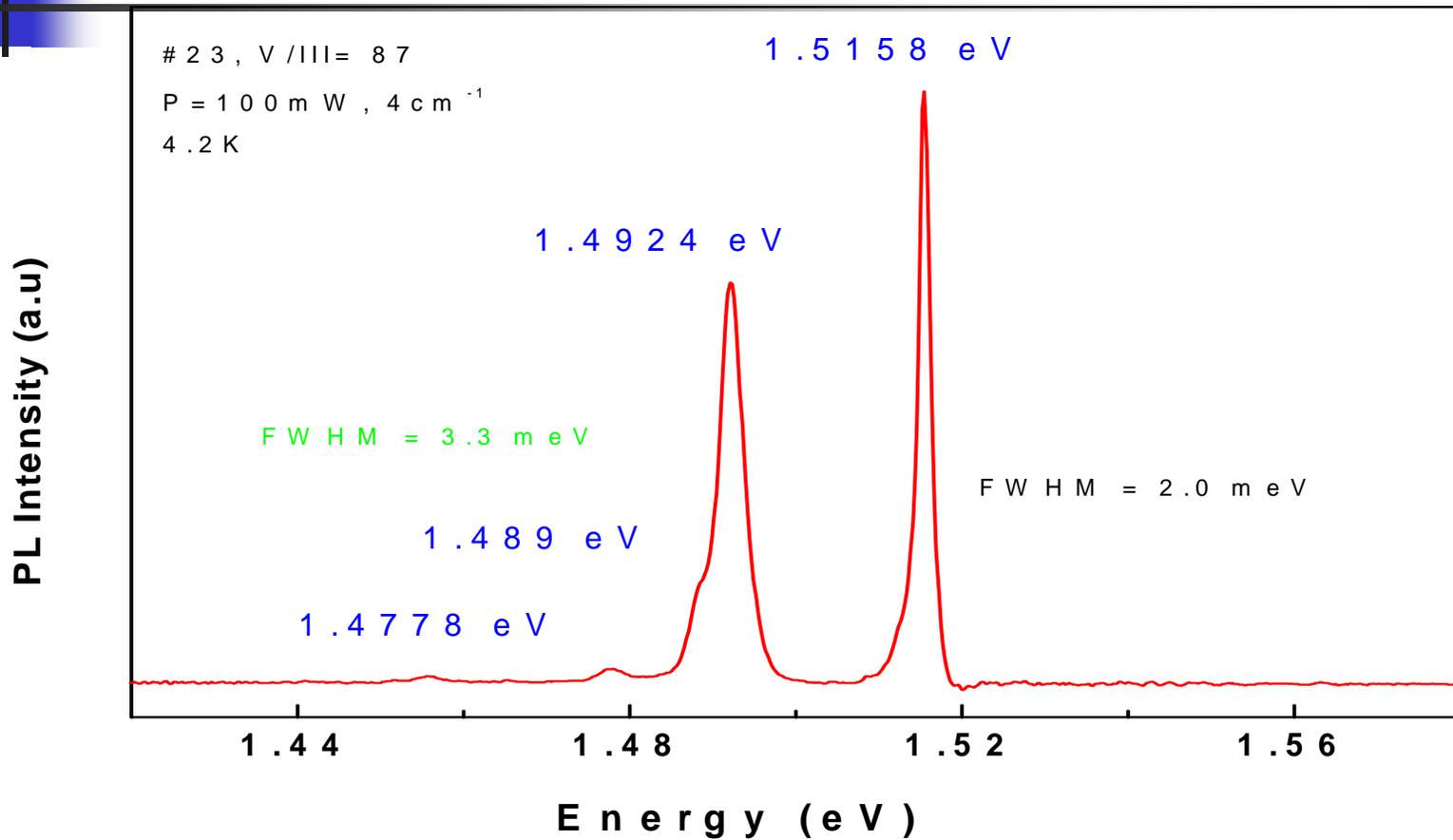
PL as a function of power of excitation source



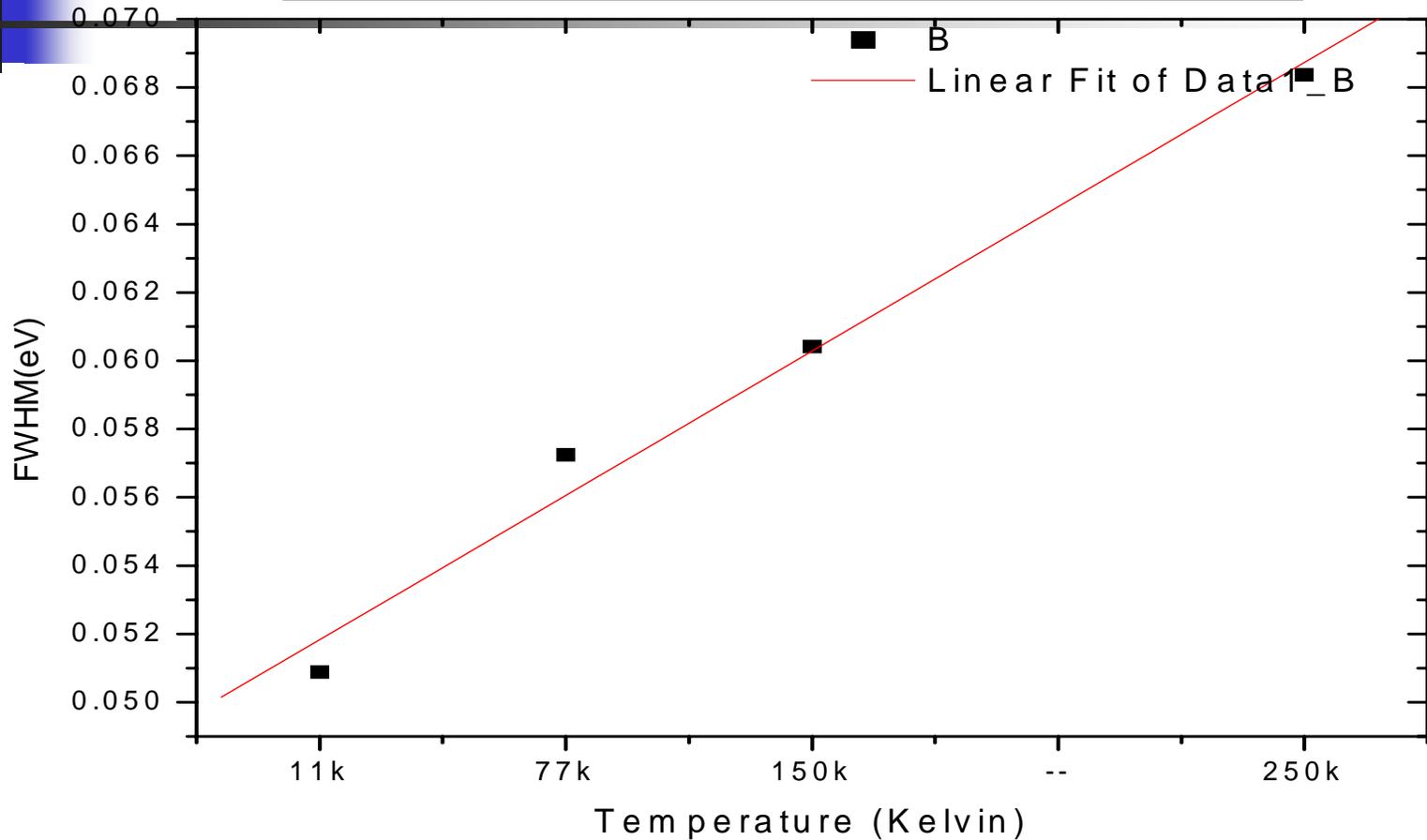
PL spectra as a function of temperature



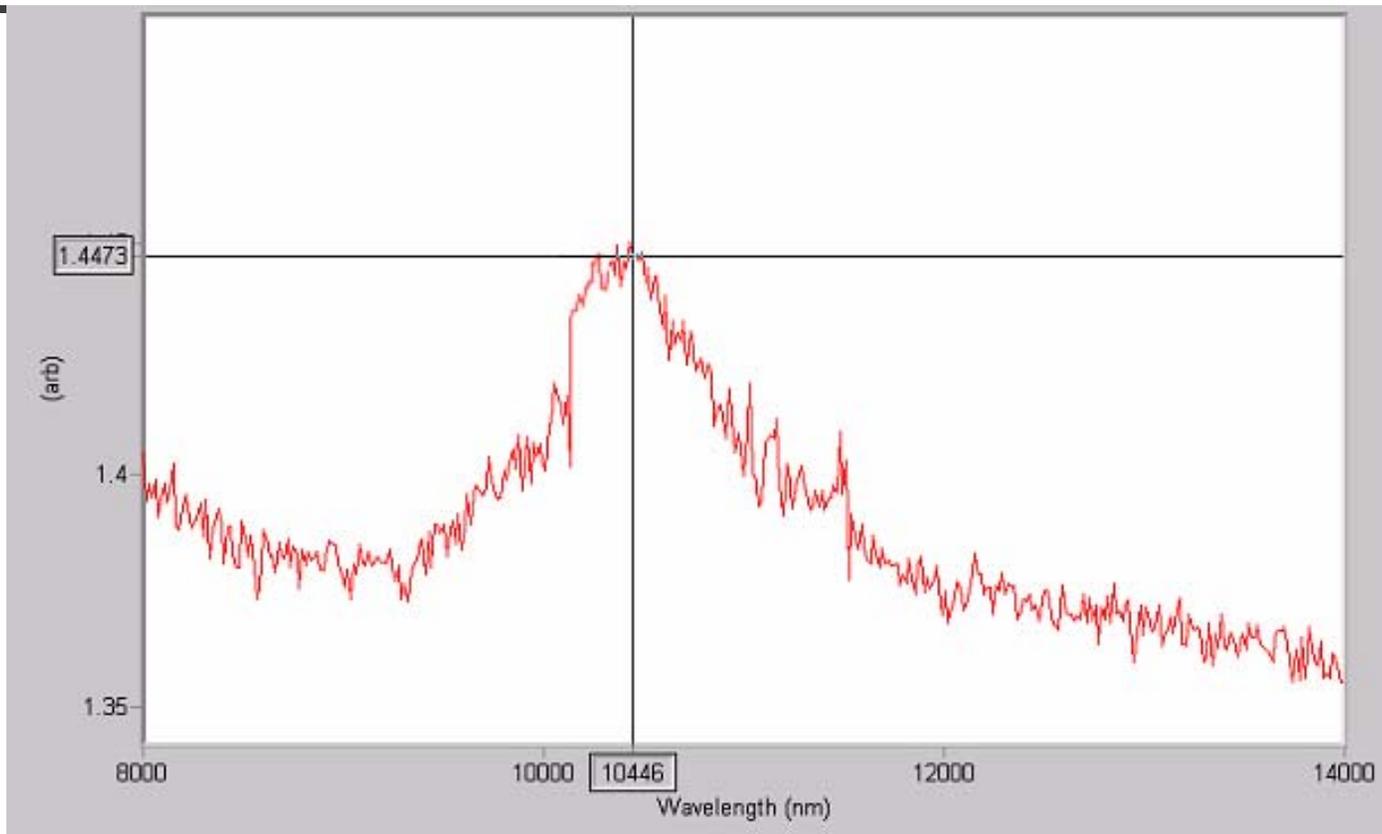
PL spectrum of undoped GaAs:

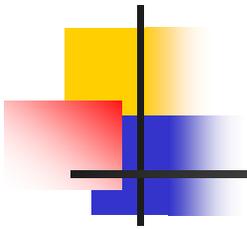


FWHM as a function of temperature



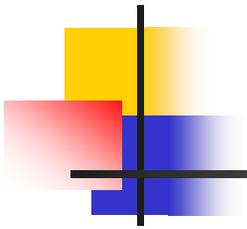
Spectral Response at 25 K





Summary

Material characterization, device processing step characterization, electrical and optical characterization were carried out for n-type GaAs/AlGaAs based QWIPs.



THANK YOU